

NAME	TITLE	PROGR. REF.	ABS. REF.
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Tuesday, September 19th

Session 3A		RF-MEMS. NEMS		
Auditorium		Chairs: Nuria Barniol, Rainer Minixhofer		
11:00-11:30	M. Tanaka	Important features of MEMS devices for practical applications	3A-1	INVITED
11:30-11:50	Stella Chang	Fabrication of a Tunable RF MEMS Inductor on Silicon in a sub-150°C Pr	3A-2	54
11:50-12:10	Kiyotaka YAMASHI	Some dependencies of field-emission current for RF-MEMS applications	3A-3	376
12:10-12:30	Jordi Teva	Fabrication of monolithic CMOS-MEMS devices using a standard 0.35um	3A-4	334
12:30-12:50	Alvaro San Paulo	Si nanowire NEMS: Fabrication and mechanical characterization of suspe	3A-5	83
12:50-13:10	Lauge Gammelgaard	Wafer Scale Fabrication of Suspended TiW Nanowires	3A-6	268

Session 3B		Electron and Ion Beam Lithography 1		
CIC1 Room		Chairs: Wilhelm H. Bruenger, Alexei Bogdanov		
11:00-11:30	E. Kolodney	C60-ion source: novel surface processes and interactions	3B-1	INVITED
11:30-11:50	Peter Hahmann	Resolution Enhancement for Variable-Shaped Beam Writers	3B-2	62
11:50-12:20	O. Wilhelmi	Nanofabrication and rapid prototyping with DualBeam instruments	3B-3	INVITED
12:20-12:40	Jacques Gierak	Sub-5 nm FIB direct patterning of nanopores	3B-4	10
12:40-13:00	Richard Langford	Reducing the Resistivity of Electron and Ion Beam Assisted Deposited Pl	3B-5	50

Session 3C		Resists and Resist Processing		
A2+A3 Room		Chair: Emile van der Drift, Alex Robinson		
11:00-11:20	Thorsten Wahlbrink	Fabrication of high aspect-ratio HSQ nano-structures through supercritical	3C-1	290
11:20-11:40	Vahid Fakhfouri	High-aspect ratio three-dimensional photoresin-based microstructures do	3C-2	411
11:40-12:00	Hiroaki Oizumi	Patterning capability of new molecular resist in EUV lithography	3C-3	192
12:00-12:20	Gaugiran Stephanie	Leaching mechanisms in immersion lithography with and without top-coat	3C-4	322
12:20-12:40	Morten Gersborg-H	Combined electron beam lithography and UV lithography in SU-8	3C-5	289
12:40-13:10	M. Vogler	Taylor-made polymers and resists - a key to the implementation of n	3C-6	INVITED

Session 4A		Micro- and Nano-systems for Biology 2		
Auditorium		Chairs: Evangelo Gogolides, Alejandro Pérez-Rodríguez		
15:45-16:05	yan jun liu	Integrated Magnetic Micro-Columns for Cancer Cell Capture and Sorting	4A-1	277
16:05-16:25	James Muys	Bioimprint: Cellular Replication for Nanoscale Imaging	4A-2	17
16:25-16:45	Yong Chen	Patterning of hydrophilic micro arrays with super-hydrophobic surrounding	4A-3	260
16:45-17:05	Pinelopi Bayiati	Biofluid transport on hydrophobic plasma deposited fluorocarbon films	4A-4	332

Session 4B		Nanoimprint Lithography 1		
CIC1 Room		Chairs:Hella C. Scheer, Helmut Schiff		
15:45-16:05	Santos Merino	A new way of manufacturing high resolution optical encoders by nanoimp	4B-1	170
16:05-16:25	Douglas Resnick	Step and Flash Imprint Lithography Templates for the 32 nm Node and Be	4B-2	438
16:25-16:45	Nicolas Bogdanski	Structure size dependent recovery of thin polystyrene layers in thermal imp	4B-3	158
16:45-17:05	Stijn Scheerlinck	UV-NIL with a DUV-Fabricated Silicon Template as a Flexible Tool for Na	4B-4	293

Session 4C		Pattern Transfer		
A2+A3 Room		Chairs: Fu-Hsiang Ko, Philippe Godignon		
15:45-16:05	Thomas TILLOCHE	Silicon cryo-etching of deep holes	4C-1	181
16:05-16:25	Xu Li	Dry etching of a device quality high-k GaxGdyOz gate oxide in CH4/H2-O	4C-2	403
16:25-16:45	Remi DUSSART	The passivation layer formation in the cryo-etching plasma process	4C-3	176
16:45-17:05	Georgios Boulousis	Mechanism of surface roughness formation and evolution during Si etchir	4C-4	431

Session 5A		Nanoscale Engineering and Fabrication 2		
Auditorium		Chair: Andris Šternberg, Gottfried Strasser		
17:30-17:50	Charan Srinivasan	Fabrication of Nanostructures using Molecular Ruler Resist	5A-1	453
17:50-18:10	Kohichi Tanaka	Detection of magnetic field for measuring current distribution in poly-Si lay	5A-2	400
18:10-18:30	Vinzenz Friedli	Mass sensor with femtogram resolution for in-situ control of focused elect	5A-3	283
18:30-18:50	Maria Villarroya	Dynamics of attoliter glycerine drops evaporation using a CMOS-MEMS n	5A-4	67

Session 5B		Micro- and Nano-systems for Biology 3		
CIC1 Room		Chair: Andreas Stemmer, Laura Lechuga		
17:30-18:00	U. Staufer	Micro- and Nanosystems for Biology and Medicine	5B-1	INVITED
18:00-18:20	Makoto Fujimaki	Nanoscale pore fabrication for high sensitivity waveguide-mode biosenso	5B-2	244
18:20-18:40	Troels Balmer Chris	Sample preparation by cell guiding using negative dielectrophoresis	5B-3	234
18:40-19:00	Michal Příbyl	Quantification of human IgG in a multichannel microfluidic chip	5B-4	114

Session 5C		Microsystems and their Fabrication 2		
A2+A3 Room		Chair: Rebecca Cheung, Philipp M Nellen		
17:30-17:50	Anthony Nichol	Two-Step Magnetic Self-Alignment of Folded Membranes for 3D Nanoma	5C-1	387
17:50-18:10	Christian David	Fabrication of diffraction gratings for hard x-ray phase contrast imaging	5C-2	301
18:10-18:30	C. Cané	Micro and Nanotechnologies for Food Safety and Quality Applicatio	5C-3	INVITED
18:30-19:00	Aitor Ezkerra	Fabrication of SU8 free standing structures embedded in microchannels f	5C-4	230